Electronic Acknowledgement Receipt FES ID: 1242892 Application Number: 10660813 Confirmation Number: 7055 Reactive ion etching for semiconductor device feature topography Title of Invention: modification First Named Inventor: Hemant P. Mungekar Customer Number: 57385 Filer: Patrick Maurice Boucher/Nina L. McNeill Filer Authorized By: Patrick Maurice Boucher Attorney Docket Number: A8067/T51700 Receipt Date: 09-OCT-2006 Filing Date: 12-SEP-2003 Time Stamp: 16:42:16 Application Type: Utility International Application Number: Payment information:

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ĺ	Document Number	Document Description	File Name	File Size(Bytes)	Multi Part	Pages	
	1		016301_051700_AMD.pdf	120173	yes	8	

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	Doc Desc	Start	End		
	Amendment - After Non-Final Rejection	1	1		
	Claims	2	6		
	Applicant Arguments/Remarks Made in an Amendment	7	8		
Warnings:		•			
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If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.

National Stage of an International Application under 35 U.S.C. 371

If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.